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PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Hiroji AGA et al.

Application No.: 09/857,803

Docket No.: 109725

Filed: June 11, 2001

For: METHOD FOR PRODUCING SOI WAFER AND SOI WAFER

REQUEST FOR CORRECTION OF PALM RECORDS

Director of the U.S. Patent and Trademark Office
Washington, D.C. 20231

Sir:

Attached is a photocopy of the original filing receipt on which errors have been corrected in red. These errors are being brought to the attention of the Patent and Trademark Office so that it may correct its records.

Respectfully submitted,

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Date: August 24, 2001

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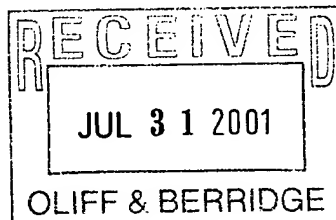
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APPLICATION NUMBER	FILING DATE	GRP ART UNIT	FIL FEE REC'D	ATTY. DOCKET NO	DRAWINGS	TOT CLAIMS	IND CLAIMS
09/857,803	06/11/2001	2811	860	109725	4	9	3

CONFIRMATION NO. 2312

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FILING RECEIPT



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Date Mailed: 07/30/2001

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Domestic Priority data as claimed by applicant

THIS APPLICATION IS A 371 OF PCT/JP00/07111 10/13/2000

Foreign Applications

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Projected Publication Date: N/A

Non-Publication Request: No

Early Publication Request: No

Title

Method For Producing Soi Wafer, and Soi Wafer

~~Method for manufacturing soi wafer, and soi wafer~~

Preliminary Class

257

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